

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Hayashi OTSUKI, et al.

SERIAL NO: New Application

GAU:

FILED: Herewith

EXAMINER:

FOR: PARTICLE-MEASURING SYSTEM AND PARTICLE-MEASURING METHOD



INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97

ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

SIR:

Applicant(s) wish to disclose the following information.

REFERENCES

- ☒ The applicant(s) wish to make of record the references listed on the attached form PTO-1449. Copies of the listed references are attached, where required, as are either statements of relevancy or any readily available English translations of pertinent portions of any non-English language references.
- ☐ A check is attached in the amount required under 37 CFR §1.17(p).

RELATED CASES

- ☐ Attached is a list of applicant's pending application(s) or issued patent(s) which may be related to the present application. A copy of the patent(s) is attached along with PTO 1449.
- ☐ A check is attached in the amount required under 37 CFR §1.17(p).

CERTIFICATION

- ☐ Each item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.
- ☐ No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

PETITION

- ☐ Applicant(s) hereby request consideration of the attached information. A check is attached in the amount of the Petition fee required under 37 CFR §1.17(i)(1).

DEPOSIT ACCOUNT

- ☒ Please charge any additional fees for the papers being filed herewith and for which no check is enclosed herewith, or credit any overpayment to deposit account number 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,  
MAIER & NEUSTADT, P.C.

Marvin J. Spivak

Registration No. 24,913

C. Irvin McClelland  
Registration Number 21,124



22850

Tel. (703) 413-3000  
Fax. (703) 413-2220  
(OSMMN 10/98)

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**STATEMENT OF RELEVANCY**

**Reference AA (5,271,264) on Form PTO-1449:**

The reference discloses ISPM in vacuum systems.

**Reference AB (5,347,138) on Form PTO-1449:**

The reference discloses ISPM in sputter coater chambers.

**Reference AW on Form PTO-1449:**

The reference discloses ISPM characterization of gas phase nucleation in a Novellus C1 WCVD process chamber.

**Reference AX on Form PTO-1449:**

The reference discloses the technique of increasing the efficiency of W-CVD by means of ISPM.

